

Abstract

In a method for making a microedged shaving surface a substrate is provided having a polymer layer applied on at least one surface thereof. An edge layer of material is applied over the polymer layer and has a hardness sufficient to support a cutting edge. At least one surface of the substrate is coated with a photoresist material that is positioned over the edge layer. The photoresist material is cured to render areal portions thereof substantially impervious to removal by etching. The photoresist material is then etched so that the areas adjacent to the substantially impervious areas create a plurality of re-entrant profiles. Any remaining photoresist material is stripped away and the edge layer is etched to the exposed discrete shaving elements, each having a peripheral edge and a sharpness sufficient to cut hair. The substrate around the discrete shaving elements is also exposed so that the cutting edges are offset from at least one surface of the substrate.